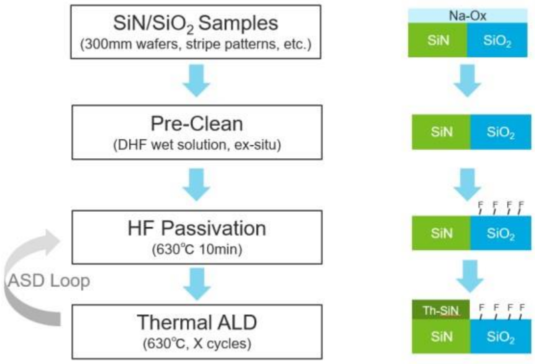
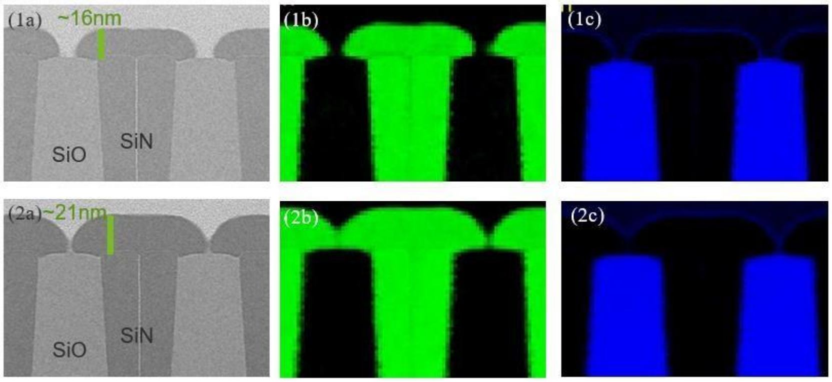
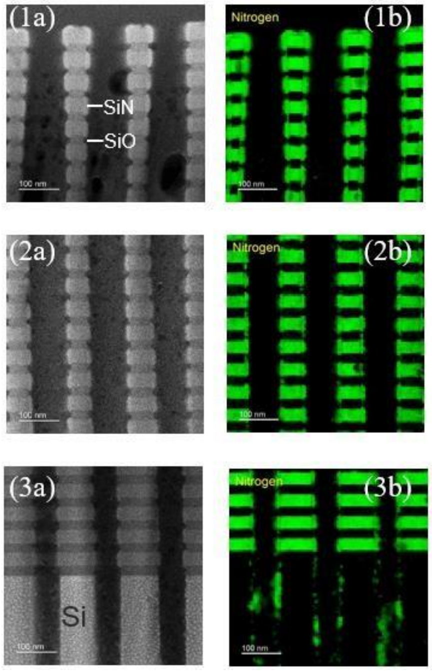


Figure 1. Process flow and schematic of ASD-Loop.



Source: TEL

Figure 2. Stripe-Patterned samples treated by (1) 16 ASD Loops and (2) 21 ASD Loops: (a) TEM image, EELS mapping of (b) nitrogen and (c) oxygen.



Source: TEL

Figure 3. SiO/SiN stacks samples (AR=65) treated by 16 ASD Loops: (a) TEM image and (b) EELS mapping of nitrogen for (1) top, (2) middle, (3) bottom of trench. Step coverage of >90% was achieved with 15 nm of ASD.